The documentation and process conversion measures necessary to comply with this revision shall be completed by 9 February 2013.

INCH-POUND

MIL-PRF-19500/563G 9 November 2012 SUPERSEDING MIL-PRF-19500/563F 5 November 2003

* PERFORMANCE SPECIFICATION SHEET

SEMICONDUCTOR DEVICE, FIELD EFFECT TRANSISTOR, P-CHANNEL, SILICON, TYPES 2N6845, 2N6845U, 2N6847, AND 2N6847U, JAN, JANTX, JANTXV, JANS, JANHC, AND JANKC

> This specification is approved for use by all Departments and Agencies of the Department of Defense.

The requirements for acquiring the product described herein shall consist of this specification sheet and MIL-PRF-19500.

1. SCOPE

- 1.1 Scope. This specification covers the performance requirements for a P-Channel, enhancement-mode, MOSFET, power transistor. Four levels of product assurance are provided for each encapsulated device type as specified in MIL-PRF-19500. Two levels of product assurance are provided for each unencapsulated device type.
- 1.2 Physical dimensions. See figure 1, TO-205AF (formerly TO-39), 2 (LCC), and figures 3 and 4 for JANHC and JANKC die dimensions.
- * 1.3 Maximum ratings. Unless otherwise specified, $T_A = +25$ °C.

Туре	P _T (1) T _C = +25°C	P _T T _A = +25°C	R _θ JC (2)	V _{DS}	V _{DG}	VGS	I _{D1} (3) (4) T _C = +25°C	I _{D2} (3) T _C = +100°C	Is	I _{DM} (5)	T _J and TSTG
	<u>W</u>	<u>W</u>	°C/W	V dc	V dc	V dc	A dc	A dc	A dc	A(pk)	<u>°C</u>
N6845, U N6847, U	20 20	0.8 0.8	6.25 6.25	-100 -200	-100 -200	±20 ±20	-4.0 -2.5	-2.6 -1.6	-4.0 -2.5	-16 -10	-55 to +150 -55 to +150

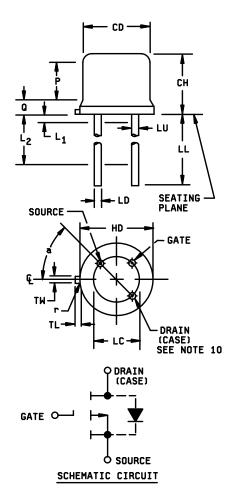
- Derate linearly 0.16 W/°C for $T_C > +25$ °C. See figure 5, thermal impedance curves.
- (1) (2)
 - The following formula derives the maximum theoretical I_D limit. I_D is limited by package and internal wires (3) and may be limited by pin diameter:

$$I_{\rm D} = \sqrt{\frac{T_{\rm JM} \text{ -} T_{\rm C}}{\left(\;R_{\,\theta \rm JC}\;\right) x \left(\;R_{\,\rm DS}\left(\;on\;\right) \text{ at } T_{\rm JM}\;\right)}}$$

- (4) See figure 6, maximum drain current graph.
- $I_{DM} = 4 \times I_{D1}$ as calculated in note 2. (5)

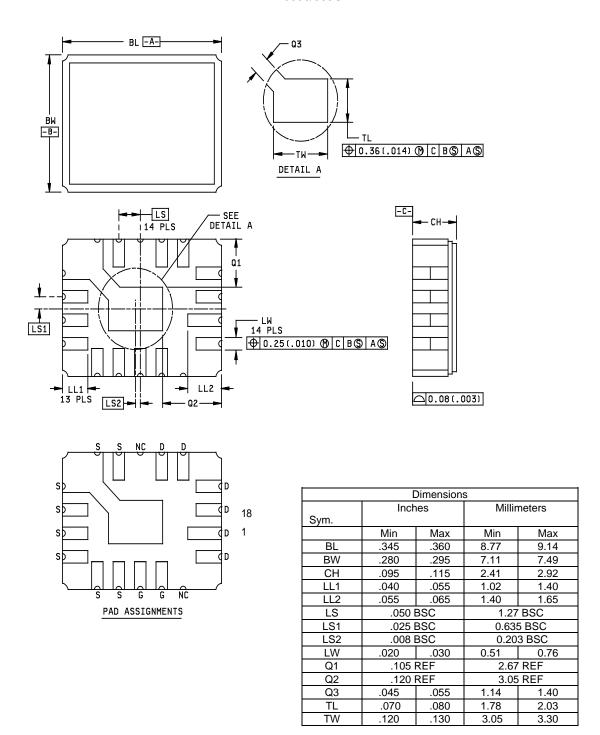
AMSC N/A FSC 5961

Comments, suggestions, or questions on this document should be addressed to DLA Land and Maritime, ATTN: VAC, P.O. Box 3990, Columbus, OH 43218-3990, or emailed to Semiconductor@dla.mil. Since contact information can change, you may want to verify the currency of this address information using the ASSIST Online database at https://assist.dla.mil/.



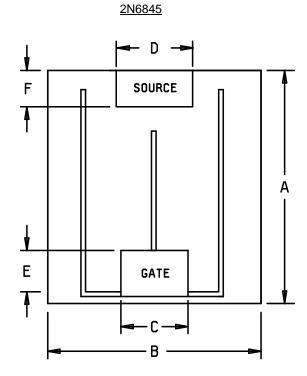
		D	imensio	ns	
Ltr	Inch	nes	Millin	neters	Notes
	Min	Max	Min	Max	
CD	.305	.335	7.75	8.51	
CH	.160	.180	4.07	4.57	
HD	.335	.370	8.51	9.39	
LC	.200	TP	5.0	6	
LD	.016	.016 .021		0.53	7, 8
LL	.500	.750	12.7	19.05	7, 8
LU	.016	.019	0.41	0.48	7, 8
L1		.050		1.27	7, 8
L2	.250		6.35		7, 8
Р	.100		2.54		5
Q		.050		1.27	4
r		.010		0.25	9
TL	.029	.045	0.74	1.14	3
TW	.028	.034	0.72	0.86	2
α	45°	TP	45	° TP	6

- 1. Dimensions are in inches. Millimeters are given for general information only.
- 2. Beyond radius (r) maximum, TW shall be held for a minimum length of .011 (0.28 mm).
- 3. Dimension TL measured from maximum HD.
- 4. Outline in this zone is not controlled.
- 5. Dimension CD shall not vary more than .010 (0.25 mm) in zone P. This zone is controlled for automatic handling.
- 6. Leads at gauge plane .054 +.001, -.000 (1.37 +0.03, -0.00 mm) below seating plane shall be within .007 (0.18 mm) radius of true position (TP) at maximum material condition (MMC) relative to tab at MMC.
- 7. LU applies between L₁ and L₂. LD applies between L₂ and LL minimum. Diameter is uncontrolled in L₁ and beyond LL minimum.
- 8. All three leads.
- 9. Radius (r) applies to both inside corners of tab.
- 10. Drain is electrically connected to the case.
- 11. In accordance with ASME Y14.5M, diameters are equivalent to φx symbology.
 - * FIGURE 1. Physical dimensions for TO-205AF.



- 1. Dimensions are in inches.
- 2. Millimeters are given for general information only.
- 3. In accordance with ASME Y14.5M, diameters are equivalent to φx symbology.

FIGURE 2. Physical dimensions for LCC.



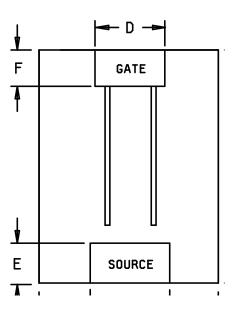
Hex-2: -100 V P-channel

Dimensions											
	Incl	hes	Millimeters								
Ltr	Min	Max	Min	Max							
Α	.106	.122	2.69	3.10							
В	.087	.103	2.21	2.62							
С	.022	.030	0.56	0.76							
D	.028	.036	0.71	0.91							
Е	.014	.022	0.36	0.56							
F	.021	.029	0.53	0.74							

- 1. Dimensions are in inches.
- 2. Millimeters are given for general information only.
- 3. The physical characteristics of the die are: the back metals are chromium, nickel, and silver. The top metal is aluminum and the back contact is the drain.
- 4. Die thickness is .0187 (0.475 mm) \pm .0050 (0.130 mm).

FIGURE 3. JANHCA and JANKCA die dimensions, 2N6845.

2N6847



Dimensions											
	Incl	hes	Millim	neters							
Ltr	Min	Max	Min	Max							
Α	.129	.145	3.28	3.68							
В	.079	.095	2.01	2.41							
С	.025	.033	0.64	0.84							
D	.027	.035	0.68	0.89							
Е	.019	.027	0.48	0.69							
F	.020	.028	0.51	0.71							

- 1. Dimensions are in inches.
- 2. Millimeters are given for general information only.
- 3. The physical characteristics of the die are: the back metals are chromium, nickel, and silver. The top metal is aluminum and the back contact is the drain.
- 4. Die thickness is .0187 (0.475 mm) \pm .0050 (0.130 mm).

FIGURE 4. JANHCA and JANKCA die dimensions, 2N6847.

* 1.4 Primary electrical characteristics at T_C = +25°C.

Туре	$\begin{aligned} & \text{Min V}(BR) \text{DSS} \\ & \text{V}_{GS} = 0 \text{ V} \\ & \text{I}_{D} = \text{-1.0 mA dc} \end{aligned}$	$V_{GS}(th)1$ $V_{DS} \ge V_{GS}$ $I_{D} = -0.25 \text{ mA dc}$	Max I _{DSS1} V _{GS} = 0 V		S(on) (1) -10 V dc
			V _{DS} = 80 percent of rated V _{DS}	T _J = +25°C at I _{D2}	T _J = +150°C at I _{D2}
	<u>V dc</u>	<u>V dc</u> <u>Min</u> <u>Max</u>	μA dc	<u>ohm</u>	<u>ohm</u>
2N6845, U 2N6847, U	-100 -200	-2.0 -4.0 -2.0 -4.0	25 25	0.60 1.50	1.20 3.15

(1) Pulsed (see 4.5.1).

2. APPLICABLE DOCUMENTS

* 2.1 <u>General</u>. The documents listed in this section are specified in sections 3, 4, or 5 of this specification. This section does not include documents cited in other sections of this specification or recommended for additional information or as examples. While every effort has been made to ensure the completeness of this list, document users are cautioned that they must meet all specified requirements of documents cited in sections 3, 4, or 5 of this specification, whether or not they are listed.

2.2 Government documents.

- * 2.2.1 <u>Specifications, standards, and handbooks</u>. The following specifications, standards, and handbooks form a part of this document to the extent specified herein. Unless otherwise specified, the issues of these documents are those cited in the solicitation or contract.
- * DEPARTMENT OF DEFENSE SPECIFICATIONS

MIL-PRF-19500 - Semiconductor Devices, General Specification for.

* DEPARTMENT OF DEFENSE STANDARDS

MIL-STD-750 - Test Methods for Semiconductor Devices.

- * (Copies of these documents are available online at https://assist.dla.mil/quicksearch/ or https://assist.dla.mil/ or from the Standardization Document Order Desk, 700 Robbins Avenue, Building 4D, Philadelphia, PA 19111-5094.)
- * 2.3 <u>Order of precedence</u>. Unless otherwise noted herein or in the contract, in the event of a conflict between the text of this document and the references cited herein, the text of this document takes precedence. Nothing in this document, however, supersedes applicable laws and regulations unless a specific exemption has been obtained.

3. REQUIREMENTS

- 3.1 General. The individual item requirements shall be as specified in MIL-PRF-19500 and as modified herein.
- 3.2 <u>Qualification</u>. Devices furnished under this specification shall be products that are manufactured by a manufacturer authorized by the qualifying activity for listing on the applicable qualified manufacturer's list (QML) before contract award (see 4.2 and 6.3).
- 3.3 <u>Abbreviations, symbols, and definitions</u>. Abbreviations, symbols, and definitions used herein shall be as defined in <u>MIL-PRF-19500</u>.

nC																			nana Caulamh
IIC.	-	 -	-	-	-	-	-	-	 -	-	-	-	-	-	-	-	-	-	 nano Coulomb

- 3.4 <u>Interface and physical dimensions</u>. The Interface and physical dimensions shall be as specified in MIL-PRF-19500, and on figures 1 (T0-205AF), 2 (LCC), 3 and 4 (die) herein.
- 3.4.1 <u>Lead material and finish</u>. Lead material shall be Kovar, Alloy 52, and a copper core is permitted. Lead finish shall be solderable in accordance with MIL-PRF-19500, MIL-STD-750, and herein. Where a choice of lead finish is desired, it shall be specified in the acquisition requirement (see 6.2).
 - 3.4.2 Internal construction. Multiple chip construction shall not be permitted.
- 3.5 <u>Marking</u>. Marking shall be in accordance with MIL-PRF-19500. At the option of the manufacturer, marking of country of origin may be omitted from the body of the transistor, but shall be retained on the initial container.
 - 3.6 Electrostatic discharge protection. The devices covered by this specification require electrostatic protection.
- 3.6.1 <u>Handling</u>. MOS devices must be handled with certain precautions to avoid damage due to the accumulation of static charge. The following handling practices shall be followed:
 - a. Devices shall be handled on benches with conductive handling devices.
 - b. Ground test equipment, tools, and personnel handling devices.
 - c. Do not handle devices by the leads.
 - d. Store devices in conductive foam or carriers.
 - e. Avoid use of plastic, rubber, or silk in MOS areas.
 - f. Maintain relative humidity above 50 percent if practical.
 - g. Care shall be exercised, during test and troubleshooting, to apply not more than maximum rated voltage to any lead.
 - h. Gate must be terminated to source, R \leq 100 k Ω , whenever bias voltage is to be applied drain to source.
- 3.7 <u>Electrical performance characteristics</u>. Unless otherwise specified herein, the electrical performance characteristics are as specified in paragraph 1.3, 1.4, and table I.
- * 3.8 Electrical test requirements. The electrical test requirements shall be as specified in table I.
- 3.9 <u>Workmanship</u>. Semiconductor devices shall be processed in such a manner as to be uniform in quality and shall be free from other defects that will affect life, serviceability, or appearance.

4. VERIFICATION

- 4.1 Classification of inspections. The inspection requirements specified herein are classified as follows:
 - a. Qualification inspection (see 4.2).
 - b. Screening (see 4.3).
 - c. Conformance inspection (see 4.4 and tables I and II).
- * 4.2 Qualification inspection. Qualification inspection shall be in accordance with MIL-PRF-19500 and table II herein.
- * 4.2.1 <u>Group E qualification</u>. Group E inspection shall be performed for qualification or re-qualification only. In case qualification was awarded to a prior revision of the specification that did not request the performance of table II tests, the tests specified in table II herein that were not performed in the prior revision shall be performed on the first inspection lot of this revision to maintain qualification.
 - 4.2.2 JANHC and JANKC die. Qualification shall be in accordance with MIL-PRF-19500.

* 4.3 <u>Screening (JANS, JANTX, and JANTXV levels only)</u>. Screening shall be in accordance with table E-IV of MIL-PRF-19500 and as specified herein. The following measurements shall be made in accordance with table I herein. Devices that exceed the limits of table I herein shall not be acceptable.

Screen (see table E-IV	Meas	urement
of MIL-PRF-19500,) (1) (2)	JANS level	JANTX and JANTXV levels
(3)	Gate stress test (see 4.3.2)	Gate stress test (see 4.3.2)
(3) (4)	Method 3470 of MIL-STD-750 (see 4.3.3), optional	Method 3470 of MIL-STD-750 (see 4.3.3), optional
(3) 3c	Method 3161 of MIL-STD-750 (see 4.3.4)	Method 3161 of MIL-STD-750 (see 4.3.4)
9	I _{GSSF1} , I _{GSSR1} , I _{DSS1} , subgroup 2 of table 1 herein	Subgroup 2 of table 1 herein
10	Method 1042 of MIL-STD-750, test condition B	Method 1042 of MIL-STD-750, test condition B
11	$\begin{split} &I_{GSSF1},I_{GSSR1},I_{DSS1},r_{DS(on)1},V_{GS(th)1}\\ &subgroup\ 2\ of\ table\ I\ herein;\\ &\Delta I_{GSSF1}=\pm20\ nA\ dc\ or\ \pm100\ percent\ of\ initial\ value,\ whichever\ is\ greater;\\ &\Delta I_{GSSR1}=\pm20\ nA\ dc\ or\ \pm100\ percent\ of\ initial\ value,\ whichever\ is\ greater;\\ &\Delta I_{DSS1}=\pm25\ \mu A\ dc\ or\ \pm100\ percent\ of\ initial\ value,\ whichever\ is\ greater \end{split}$	I _{GSSF1} , I _{GSSR1} , I _{DSS1} , r _{DS(on)1} , V _{GS(th)1} subgroup 2 of table I herein
12	Method 1042 of MIL-STD-750, test condition A, t = 240 hours	Method 1042 of MIL-STD-750, test condition A
13	Subgroups 2 and 3 of table I herein; $\Delta I_{GSSF1} = \pm 20 \text{ nA dc or } \pm 100 \text{ percent of initial value, whichever is greater;} \\ \Delta I_{GSSR1} = \pm 20 \text{ nA dc or } \pm 100 \text{ percent of initial value, whichever is greater;} \\ \Delta I_{DSS1} = \pm 25 \mu\text{A dc or } \pm 100 \text{ percent of initial value, whichever is greater} \\ \Delta r_{DS(on)1} = \pm 20 \text{ percent of initial value} \\ \Delta V_{GS(th)1} = \pm 20 \text{ percent of initial value}$	Subgroup 2 of table I herein; $ \Delta I_{GSSF1} = \pm 20 \text{ nA dc or } \pm 100 \text{ percent of initial } $ value, whichever is greater; $ \Delta I_{GSSR1} = \pm 20 \text{ nA dc or } \pm 100 \text{ percent of initial } $ value, whichever is greater; $ \Delta I_{DSS1} = \pm 25 \mu \text{A dc or } \pm 100 \text{ percent of initial } $ value, whichever is greater $ \Delta r_{DS(on)1} = \pm 20 \text{ percent of initial value} $ $ \Delta V_{GS(th)1} = \pm 20 \text{ percent of initial value} $

- (1) At the end of the test program, I_{GSSF1} , I_{GSSR1} , and I_{DSS1} are measured.
- (2)
- An out-of-family program to characterize I_{GSSF1}, I_{GSSR1}, I_{DSS1}, and V_{GS(th)1} shall be invoked. Shall be performed anytime after temperature cycling, screen 3a. JANTX and JANTXV levels do not need to be repeated in screening requirements.
 - This test need not be performed in group A when performed as a screen.

- 4.3.1 <u>Screening (JANHC and JANKC)</u>. Screening of die shall be in accordance with MIL-PRF-19500. As a minimum, die shall be 100-percent probed in accordance with table I, subgroup 2.
 - 4.3.2 Gate stress test. Apply $V_{GS} = \pm 30 \text{ V}$ minimum for $t = 250 \mu \text{s}$ minimum.
 - 4.3.3 <u>Unclamped inductive switching</u>.
 - a. Peak current (I_D)rated I_{D1}.
 - b. Peak gate voltage (V_{GS}).....-10 V.
 - c. Gate to source resistor (R_{GS})......25°C $\leq R_{GS} \leq 200$ °C.
 - d. Initial case temperature (T_C)+25°C, +10°C, -5°C.

 - f. Number of pulses to be applied1 pulse minimum.
 - g. Pulse repetition rate......None.
- * 4.3.4 <u>Thermal impedance</u>. The thermal impedance measurements shall be performed in accordance with method 3161 of <u>MIL-STD-750</u> using the guidelines in that method for determining I_M , I_H , t_H , t_{SW} , (and V_H where appropriate). Measurement delay time (t_{MD}) = 70 μ s max. See table II, group E, subgroup 4 herein.
- * 4.4 Conformance inspection. Conformance inspection shall be in accordance with MIL-PRF-19500.
- 4.4.1 <u>Group A inspection</u>. Group A inspection shall be conducted in accordance with <u>MIL-PRF-19500</u> and <u>table I</u> herein. Electrical measurements (end-points) shall be in accordance with the inspections of <u>table I</u>, subgroup 2 herein.
- 4.4.2 <u>Group B inspection</u>. Group B inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-VIA (JANS) and table E-VIB (JAN, JANTX, and JANTXV) of <u>MIL-PRF-19500</u> and herein. Electrical measurements (end-points) shall be in accordance with the inspections of <u>table I</u>, subgroup 2 herein.
- * 4.4.2.1 Group B inspection table E-VIA (JANS) of MIL-PRF-19500.

	<u>Subgroup</u>	<u>Method</u>	Condition
	В3	1051	Test condition G.
	B4	1042	Test condition D; 2,000 cycles. The heating cycle shall be 1 minute minimum.
	B5	1042	Accelerated steady-state operation life; test condition A; V_{DS} = rated T_A = +175°C, t = 120 hours. Read and record $V_{(BR)DSS}$ (pre and post at 1 mA = I_D . Read and record I_{DSS} (pre and post). Deltas for $V_{(BR)DSS}$ shall not exceed 10 percent and I_{DSS} shall not exceed +25°A.
			Accelerated steady-state gate stress; condition B, V_{GS} = rated, T_A = +175°C, t = 24 hours.
*	B5	2037	Bond strength; test condition D.
*	В6	3161	Thermal resistance, see 4.3.4, $R_{\theta JC(max)} = 2.69^{\circ}C/W$.

* 4.4.2.2 Group B inspection, table E-VIB (JAN, JANTX, and JANTXV) of MIL-PRF-19500.

	Subgroup	Method	Condition
	B2	1051	Test condition G, 25 cycles.
	ВЗ	1042	Test condition D, 2,000 cycles. The heating cycle shall be 1 minute minimum.
*	В3	2037	Test condition D. All internal bond wires for each device shall be pulled separately.

^{* 4.4.3 &}lt;u>Group C inspection</u>. Group C inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-VII of MIL-PRF-19500 and as follows. Electrical measurements (end-points) shall be in accordance with the inspections of table I, subgroup 2 herein.

	Subgroup	Method	<u>Condition</u>
	C2	2036	Test condition E (not required for LCC).
*	C5	3161	Thermal resistance, see 4.3.4, $R_{\theta JC(max)} = 2.69^{\circ}C/W$.
	C6	1042	Test condition D, 6,000 cycles. The heating cycle shall be 1 minute minimum.

- 4.4.4 <u>Group E inspection</u>. Group E inspection shall be conducted in accordance with the conditions specified for subgroup testing in table E-IX of MIL-PRF-19500 and as specified in table II herein. Electrical measurements (endpoints) shall be in accordance with table I, subgroup 2 herein.
 - 4.5 Methods of inspection. Methods of inspection shall be as specified in the appropriate tables and as follows.
 - 4.5.1 Pulse measurements. Conditions for pulse measurement shall be as specified in section 4 of MIL-STD-750.

* TABLE I. Group A inspection.

	Inspection <u>1</u> /		MIL-STD-750	Symbol	Lir	nits	Unit
		Method	Condition		Min	Max	
	Subgroup 1						
	Visual and mechanical inspection	2071					
	Subgroup 2						
r	Thermal impedance 2/	3161	See 4.3.4	Z_{\thetaJC}			°C/W
	Breakdown voltage, drain to source	3407	Bias condition C, $V_{GS} = 0V$, $I_D = -1$ mA dc	$V_{(BR)DSS} \\$			
	2N6845, 2N6845U 2N6847, 2N6847U				-100 -200		V dc V dc
	Gate to source voltage (threshold)	3403	$V_{DS} \geq V_{GS}, \ I_D = -0.25 \ mA$	$V_{GS(th)1}$	-2.0	-4.0	V dc
	Gate current	3411	Bias condition C, $V_{GS} = \pm 20 \text{ V dc}$ $V_{DS} = 0 \text{ V dc}$	I _{GSS1}		±100	nA dc
	Drain current	3413	Bias condition C, $V_{GS} = 0 \text{ V dc}$, $V_{DS} = 80 \text{ percent of rated } V_{DS}$	I _{DSS1}		-25	μA dc
	Static drain to source on-state resistance	3421	$V_{GS} = -10 \text{ V dc}$, condition A, pulsed (see 4.5.1), $I_D = \text{rated } I_{D2}$	r _{DS(on)1}			
	2N6845, 2N6845U 2N6847, 2N6847U		(see 1.3) $I_D = -2.60 \text{ A dc}$ $I_D = -1.60 \text{ A dc}$			0.60 1.50	Ω Ω
	Static drain to source on-state resistance	3421	$V_{GS} = -10 \text{ V dc}$, condition A, pulsed (see 4.5.1), $I_D = \text{rated } I_{D1}$,	r _{DS(on)2}			
	2N6845, 2N6845U 2N6847, 2N6847U		(see 1.3) I _D = -4.0 A dc I _D = -2.5 A dc			0.65 1.52	Ω
	Forward voltage	4011	$V_{GS} = 0 \text{ V dc}$, $I_D = \text{rated } I_{D1}$, pulsed	V_{SD}			V
	2N6845, 2N6845U 2N6847, 2N6847U		(see 4.5.1) $I_S = -4.0 \text{ A dc}$ $I_S = -2.5 \text{ A dc}$			-4.8 -4.8	V V
	· · · · · · · · · · · · · · · · · · ·		9			_	_

See footnote at end of table.

MIL-PRF-19500/563G

* TABLE I. Group A inspection - Continued.

Inspection 1/		MIL-STD-750	Symbol	Liı	mits	Unit
	Method	Condition		Min	Max	
Subgroup 3						
High temperature operation:		$T_C = T_J = +125^{\circ}C$				
Gate current	3411	Bias condition C, $V_{GS} = \pm 20 \text{ V dc}$, $V_{DS} = 0 \text{ V dc}$,	I _{GSS2}		±200	nA dc
Drain current	3413	Bias condition C, $V_{GS} = 0 \text{ V dc}$, $V_{DS} = 80 \text{ percent of rated } V_{DS}$	I _{DSS2}		-0.25	mA dc
Gate to source voltage (threshold)	3403	$V_{DS} \ge V_{GS}$, $I_D =25 \text{ mA}$	$V_{\text{GS(th)2}}$	-1.0		V dc
Static drain to source on-state resistance 2N6845, 2N6845U 2N6847, 2N6847U	3421	V_{GS} = -10 V dc, pulsed (see 4.5.1), I_D = rated I_{D2} I_D = -2.60 A dc I_D = -1.60 A dc	r _{DS(on)3}		1.08 2.94	Ω
Low temperature operation:		$T_C = T_J = -55$ °C				
Gate to source voltage (threshold)	3403	$V_{DS} \ge V_{GS}$, $I_D =25 \text{ mA}$	$V_{\text{GS(th)3}}$		-5.0	V dc
Subgroup 4						
Switching time test	3472	I_D = rated I_{D1} ; V_{GS} = -10 V dc; Gate drive impedance = 7.5 Ω ;				
Turn-on delay time 2N6845, 2N6845U 2N6847, 2N6847U		$V_{DD} = -40 \text{ V dc}$ $V_{DD} = -75 \text{ V dc}$	$t_{d(on)}$		60 50	ns ns ns
Rise time 2N6845, 2N6845U 2N6847, 2N6847U		$V_{DD} = -40 \text{ V dc}$ $V_{DD} = -75 \text{ V dc}$	t _r		100 70	ns ns ns
Turn-off delay time 2N6845, 2N6845U 2N6847, 2N6847U		$V_{DD} = -40 \text{ V dc}$ $V_{DD} = -75 \text{ V dc}$	$t_{\text{d(off)}}$		50 40	ns ns
Fall time 2N6845, 2N6845U 2N6847, 2N6847U		$V_{DD} = -40 \text{ V dc}$ $V_{DD} = -75 \text{ V dc}$	t _f		70 50	ns ns

See footnotes at end of table.

* TABLE I. Group A inspection - Continued.

Inspection <u>1</u> /	MIL-STD-750		Symbol	Limits		Unit
	Method	Condition		Min	Max	
Subgroup 5						
Single pulse unclamped inductive switching 3/	3470	See 4.3.3, 116 devices, c = 0				
Electrical measurements		See table I, subgroup 2				
Safe operating area test (high voltage)	3474	See figure 7 $t_p = 10$ ms, $V_{DS} = 80$ percent of rated V_{DS} , $V_{DS} \le 200$ V dc max.				
Electrical measurements		See table I, subgroup 2				
Subgroup 6						
Not applicable						
Subgroup 7						
Gate charge	3471	Condition B				
On-state gate charge 2N6845, 2N6845U 2N6847, 2N6847U			Q _{g(on)}		16.3 15.0	nC nC
Gate to source charge 2N6845, 2N6845U 2N6847, 2N6847U			Q_gs		4.7 3.2	nC nC
Gate to drain charge 2N6845, 2N6845U 2N6847, 2N6847U			Q_gd		9.0 8.4	nC nC
Reverse recovery time	3473	$eq:discrete_$	t _{rr}			
2N6845, 2N6845U 2N6847, 2N6847U		I _F = -4 A I _F = -2.5 A			200 300	ns ns

^{1/} For sampling plan, see MIL-PRF-19500.
2/ This test required for the following end-point measurements only: Group B, subgroups 2 and 3 (JANTXV).
Group B, subgroups 3 and 4 (JANS).

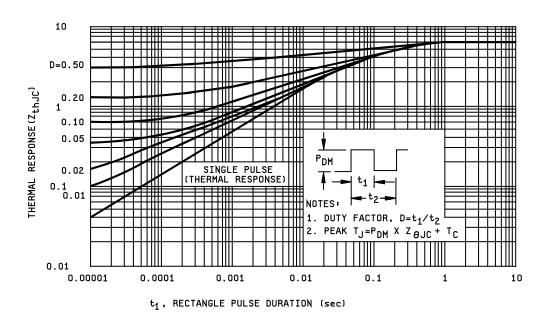
Group C, subgroup 2 and 6. Group E, subgroup 1.

^{3/} This test is optional if performed as a 100 percent screen.

* TABLE II. Group E inspection (all quality levels) for qualification or re-qualification only.

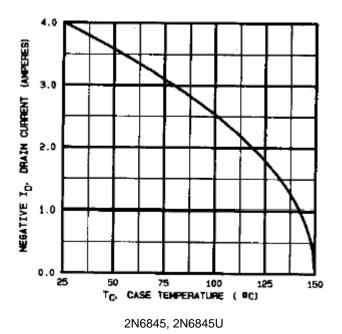
Inspection 1/		MIL-STD-750	Qualification inspection	
<u>"</u>	Method	Conditions	inspection	
Subgroup 1			12 devices c = 0	
Temperature cycling	1051	Condition G, 500 cycles		
Hermetic seal	1071			
Fine leak Gross leak				
Electrical measurements		See table I, subgroup 2		
Subgroup 2 2/			45 devices	
Steady-state reverse bias	1042	Condition A, 1,000 hours	c = 0	
Electrical measurements		See table I, subgroup 2		
Steady-state gate bias	1042	Condition B, 1,000 hours		
Electrical measurements		See table I, subgroup 2		
Subgroup 4			Sample size N/A	
Thermal impedance curves		See MIL-PRF-19500.	IVA	
Subgroup 5				
Not applicable				
Subgroup 10				
Commutating diode for safe operating area test procedure for measuring dv/dt during reverse recovery of power MOSFET transistors or insulated gate bipolar transistors	3476		22 devices c = 0	

 $[\]underline{1}/$ JANHC and JANKC devices are qualified in accordance with MIL-PRF-19500. $\underline{2}/$ A separate sample may be pulled for each test.



2N6845, 2N6845U, 2N6847 and 2N6847U

FIGURE 5. Thermal impedance curve.



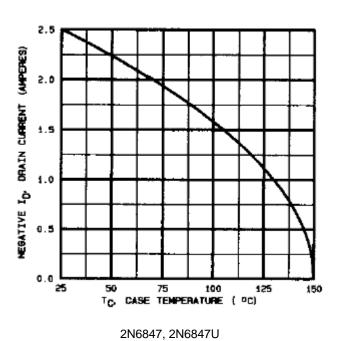


FIGURE 6. Maximum drain current versus case temperature graphs.

ACTIVE REGION - 2N6845, 2N6845U

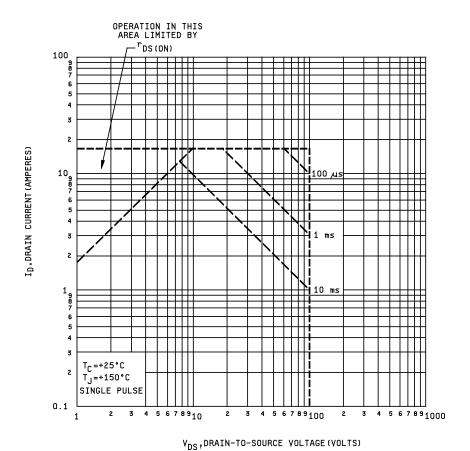


FIGURE 7. Maximum safe operating area.

ACTIVE REGION - 2N6847, 2N6847U

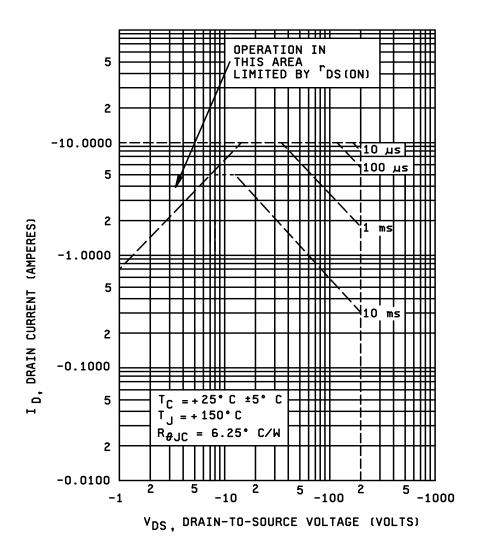


FIGURE 7. Maximum safe operating area - Continued.

5. PACKAGING

* 5.1 <u>Packaging</u>. For acquisition purposes, the packaging requirements shall be as specified in the contract or order (see 6.2). When packaging of materiel is to be performed by DoD personnel, these personnel need to contact the responsible packaging activity to ascertain requisite packaging requirements. Packaging requirements are maintained by the Inventory Control Points' packaging activity within the Military Department or Defense Agency, or within the Military Departments' System Command. Packaging data retrieval is available from the managing Military Departments' or Defense Agency's automated packaging files, CD-ROM products, or by contacting the responsible packaging activity.

6. NOTES

- * (This section contains information of a general or explanatory nature that may be helpful, but is not mandatory. The notes specified in MIL-PRF-19500 are applicable to this specification.)
- * 6.1 <u>Intended use</u>. Semiconductors conforming to this specification are intended for original equipment design applications and logistic support of existing equipment.
- * 6.2 Acquisition requirements. Acquisition documents should specify the following:
 - a. Title, number, and date of this specification.
 - b. Packaging requirements (see 5.1).
 - c. Lead material and finish (see 3.4.1).
 - d. Product assurance level and type designator.
 - e. For die acquisition, specify the JANHC or JANKC letter version (see figures 3 and 4).
- * 6.3 Qualification. With respect to products requiring qualification, awards will be made only for products which are, at the time of award of contract, qualified for inclusion in Qualified Manufacturers List (QML 19500) whether or not such products have actually been so listed by that date. The attention of the contractors is called to these requirements, and manufacturers are urged to arrange to have the products that they propose to offer to the Federal Government tested for qualification in order that they may be eligible to be awarded contracts or orders for the products covered by this specification. Information pertaining to qualification of products may be obtained from DLA Land and Maritime, ATTN: VQE, P.O. Box 3990, Columbus, OH 43218-3990 or e-mail vqe.chief@dla.mil. An online listing of products qualified to this specification may be found in the Qualified Products Database (QPD) at https://assist.dla.mil.
- 6.4 <u>Cross-reference and complement list</u>. Parts from this specification may be used to replace the following commercial Part or Identifying Number (PIN's). The term PIN is equivalent to the term part number which was previously used in this specification.

Preferred types	Commercial types (1)		
2N6845	IRFF9120, IRFF9121, IRFF9122, IRFF9123		
2N6847	IRFF9220, IRFF9221, IRFF9222, IRFF9223		
2N6845U	IRFE9120, IRFE9121, IRFE9132, IRFE9123		
2N6847U	IRFE9220, IRFE9221, IRFE9222, IRFE9223		

6.5 <u>Suppliers of JANHC and JANKC die.</u> The qualified die suppliers with the applicable letter version (example, JANHCA2N6845) will be identified on the QML.

6.6 <u>Changes from previous issue</u>. The margins of this specification are marked with asterisks to indicate where changes from the previous issue were made. This was done as a convenience only and the Government assumes no liability whatsoever for any inaccuracies in these notations. Bidders and contractors are cautioned to evaluate the requirements of this document based on the entire content irrespective of the marginal notations and relationship to the last previous issue.

Custodians:

Army - CR Navy - EC Air Force - 85 NASA - NA DLA - CC Preparing activity: DLA - CC

(Project 5961-2012-049)

Review activities:

Army - MI, SM Navy - AS, MC Air Force - 19, 99

* NOTE: The activities listed above were interested in this document as of the date of this document. Since organizations and responsibilities can change, you should verify the currency of the information above using the ASSIST Online database at https://assist.dla.mil/.